

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: )  
 ) Examiner:  
 Yuichiro Nakamura et al. )  
 ) Group Art Unit:  
 Application No.: )  
 )  
 Corresponding International Filing No.: )  
 PCT/JP2005/002209 )  
 )  
 Filed: Herewith )  
 )  
 For: SPUTTERING TARGET WITH )  
 FEW SURFACE DEFECTS, AND )  
 SURFACE PROCESSING )  
 METHOD THEREOF )

Mail Stop PCT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**FIRST PRELIMINARY AMENDMENT**

Sir:

**Before calculating the filing fee**, please amend the above-identified patent application as follows.

**Amendments to the Claims** are reflected in the listing of claims which begins on page two of this paper.

**Remarks** begin on page three of this paper.